# PhableR 100

revolutionary photo-lithography system for research and production



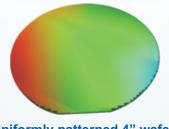
Resolution of a stepper
Simplicity of a mask aligner
Low-cost solution for photonic patterning



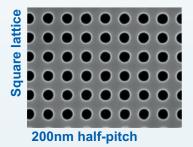
## PhableR 100

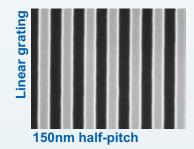
#### WHAT IS THE PhableR 100 TOOL?

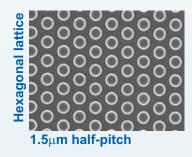
The PhableR 100 tool provides unprecedented ability to print high resolution periodic structures in a low-cost photolithography system. It is similar to a conventional mask-aligner where a photoresist coated wafer is put in proximity to a mask and exposed by a beam of UV light, but thanks to the break-through PHABLE exposure technology of Eulitha the resolution is no longer limited by diffraction. In the "PHABLE" mode, sub-micron linear gratings and 2D patterns such as hexagonal and square lattices are printed with high uniformity and quality. In the "mask aligner" mode, micron scale features can be printed easily.



Uniformly patterned 4" wafer







#### **BENEFITS**

- · High resolution below 300nm pitch
- Full-field exposure
- Non-contact: protects masks from damage and contamination
- Practically unlimited depth-of-focus
- Suitable for non-flat substrates (e.g. epi-wafers)
- High uniformity
- Overlay alignment capability
- Commercially available photoresists and materials
- Conventional mask (Cr-on-glass)
- Frequency multiplication

### **APPLICATIONS**



#### **SPECIFICATIONS**

Resolution	< 150nm half-pitch (linear grating)
Wafer size	up to 100mm diameter
Mask format	5"
Illumination uniformity	< 3%
Pitch range	300nm - 3μm
Resist thickness	> 1µm
Operation	Manual load - automatic exposure
Control	Touch panel

